



Pivotal Introduces GFM-800A System—In Situ Gas Flow Monitoring With Absolute Accuracy of $\pm 0.5\%$

**GFM-800A PROVIDES NECESSARY ACCURACY FOR ADVANCED NODE
WAFER PROCESSING APPLICATIONS**

Pleasanton, CA.—May 25, 2010—Pivotal Systems Corporation, the leader in advanced process monitoring and control solutions, today announced the release of its GFM-800A gas flow monitoring system. The GFM-800A improves upon the available GFM-800 system by allowing for a highly accurate calibration of the gas stick volume, thereby guaranteeing an absolute flow accuracy measurement of $\pm 0.5\%$.

“With the GFM-800 system, our customers calibrate our system’s volume using a golden MFC or a rate of pressure rise calculation,” said Joseph Monkowski, Pivotal’s President and Chief Technology Officer, “Therefore its accuracy is as good as the offline system being used to calibrate the volume. With the GFM-800A we have included a NIST traceable volume that fits onto the gas stick allowing for a highly accurate calculation of the volume. This approach allows us to guarantee a flow measurement of $\pm 0.5\%$ of actual flow since we know the volume to a high degree of accuracy.”

“The benefit of the GFM-800A is for advanced nodes where accuracy of gas flow, especially at low flow rates, is critical,” said Mukund Venkatesh, Pivotal’s Vice President of Marketing, “Many IDMs today need gas flows that are accurate to $\pm 0.5\text{-}1\%$ during a critical etch or deposition process. While the MFCs often report stable operation within a 0.5% window, the reality is that they vary much more than 0.5% and often into single digit percentages. By guaranteeing in situ gas flow measurements to an accuracy of $\pm 0.5\%$, the GFM-800A system is an invaluable tool to combat yield and chamber matching issues at these advanced technology nodes.”

About Pivotal Systems

Pivotal Systems Corporation provides best-in-class monitoring and process control technology for the semiconductor manufacturing industry. Pivotal’s vision is to enable an order of magnitude increase in fab productivity and capital efficiency for current and future technology nodes. This vision is achieved through its real time in situ process monitoring and control solutions. Founded in 2003 and based in Pleasanton, California, the company is led by veterans from the semiconductor and high-tech industries. For more information about Pivotal, please visit www.pivotalsys.com, or send an email to info@pivotalsys.com.